

Reference 5: Japanese Patent Application Laid Open No. H6-75364

Title of the Invention: Mask for Exposure

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Extract:

See Fig. 1. A pellicle film 16a is secured to pellicle frames 15a and 15b using adhesive (a) 17a and 17b, and a pellicle film 16b is secured to pellicle frames 15c and 15d using adhesive (a) 17c and 17d. An adhesive (b) 19a and an adhesive (c) 20a are bonded using a double-faced tape 18a between the pellicle frame 15a and a mask 11. The same holds true for between the mask 11 and the pellicle frames 15b, 15c and 15d.

*[Faint handwritten notes]*

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[illegible]

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